

Notice of References Cited

Application/Control No.

09/632,425

Applicant(s)/Patent Under
Reexamination
GEIGER ET AL.

Examiner

Lisa A Kilday

Art Unit

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U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
X	A	US-5,804,509	09-1998	Cho, Gyung-Su	438/790
X	B	US-6,180,507	01-2001	Lan, Shih-Ming	438/618
	C	US-			
	D	US-			
	E	US-			
	F	US-			
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	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
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	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
X	U	Kwok et al. ("Surface related phenomena in Integrated PECVD/Ozone-TEOS SACVD Processes for sub-half micron gap fill: electrostatic effects", J. Electrochem. Soc., vol. 141, no. 8, Aug. 1994).
	V	
	W	
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.